

Notice of References Cited

Application/Control No.

09/800,851

Applicant(s)/Patent Under
Reexamination
HUTTON ET AL. *W*

Examiner

Albert Wang

Art Unit

2115

Page 1 of 1

U.S. PATENT DOCUMENTS

| * | | Document Number Country Code-Number-Kind Code | Date MM-YYYY | Name | Classification |
|---|---|--|-----------------|------------------|----------------|
| | A | US-6,577,148 | 06-2003 | DeHaven et al. | 324/765 |
| | B | US-6,553,545 | 04-2003 | Stinson et al. | 716/4 |
| | C | US-6,535,013 | 03-2003 | Samaan, Samie B. | 324/765 |
| | D | US-5,266,890 | 11-1993 | Kumbasar et al. | 324/158.1 |
| | E | US- | | | |
| | F | US- | | | |
| | G | US- | | | |
| | H | US- | | | |
| | I | US- | | | |
| | J | US- | | | |
| | K | US- | | | |
| | L | US- | | | |
| | M | US- | | | |

FOREIGN PATENT DOCUMENTS

| * | | Document Number Country Code-Number-Kind Code | Date MM-YYYY | Country | Name | Classification |
|---|---|--|-----------------|---------|------|----------------|
| | N | | | | | |
| | O | | | | | |
| | P | | | | | |
| | Q | | | | | |
| | R | | | | | |
| | S | | | | | |
| | T | | | | | |

NON-PATENT DOCUMENTS

| * | | Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages) |
|---|---|---|
| | U | M. Hatzilambrou, A.R. Neureuther, and C.J. Spanos, "Ring Oscillator Sensitivity to Spatial Process Variation", Presented: 1st International Workshop on Statistical Metrology, June 1996. |
| | V | |
| | W | |
| | X | |

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.